

L Number	Hits	Search Text	DB	Time stamp
1	123	(resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:03
2	53001	pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 18:58
3	374465	(metal metallic al aluminum) near (layer coating film)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 18:58
4	764	substrate with carbon with plurality	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:00
5	0	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate)) with ((metal metallic al aluminum) near (layer coating film)) with (substrate with carbon with plurality)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:01
6	0	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate)) same ((metal metallic al aluminum) near (layer coating film)) same (substrate with carbon with plurality)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 18:59
7	43305	substrate with carbon	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:03
8	9	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate)) with ((metal metallic al aluminum) near (layer coating film)) with (substrate with carbon)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:01
9	2910	(resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:02
10	276217	(magnetic magneto-optical mo!) near2 (disk recording)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:38
11	10200	(substrate near2 carbon)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:03
12	481	substrate near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:03

14	0	((magnetic magneto-optical mo!) near2 (disk recording)) and (((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation)))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) ((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation)))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate))) same (((substrate near2 carbon)) (substrate near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:04
13	7	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) ((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation)))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate))) same (((substrate near2 carbon)) (substrate near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:04
15	0	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) ((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation)))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate))) same (((substrate near2 carbon)) (substrate near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3)))) same ((metal metallic al aluminum) near (layer coating film))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:05
16	0	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate)) same (((substrate near2 carbon)) (substrate near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3)))) same ((metal metallic al aluminum) near (layer coating film))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:05
17	114	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate)) and (((substrate near2 carbon)) (substrate near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3)))) and ((metal metallic al aluminum) near (layer coating film))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:05

18	15	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate)) and (((substrate near2 carbon)) (substrate near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3)))) and ((metal metallic al aluminum) near (layer coating film)) and ((magnetic magneto-optical mo!) near2 (disk recording)))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:15
19	199	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) ((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate))) same ((metal metallic al aluminum) near (layer coating film))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:27
21	0	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) ((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate))) same ((metal metallic al aluminum) near (layer coating film))) same ((magnetic magneto-optical mo!) near2 (disk recording)))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:16
22	5	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) ((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate))) same ((metal metallic al aluminum) near (layer coating film))) and ((magnetic magneto-optical mo!) near2 (disk recording)))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:16
23	2	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) ((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate))) same ((metal metallic al aluminum) near (layer coating film))) same substrate same carbon	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:19

20	99	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) ((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate))) same ((metal metallic al aluminum) near (layer coating film)) same substrate	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:20
24	36	((((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) ((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate))) same ((metal metallic al aluminum) near (layer coating film))) and (recording disk disc)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:24
25	19	((((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) ((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate))) same ((metal metallic al aluminum) near (layer coating film))) and (((magnetic magneto-optical mo!) near2 (disk recording)) disk disc recording optical).ti.)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:25
26	7	(((((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) ((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate))) same ((metal metallic al aluminum) near (layer coating film))) and (((magnetic magneto-optical mo!) near2 (disk recording)) disk disc recording optical).ti.) not (((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) ((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate))) same ((metal metallic al aluminum) near (layer coating film))) and (recording disk disc))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:25

27	62	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) ((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate))) with ((metal metallic al aluminum) near (layer coating film)))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:27
28	0	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) ((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate))) with ((metal metallic al aluminum) near (layer coating film))) same ((substrate with carbon) ((magnetic magneto-optical mo!) near2 (disk recording)) ((substrate near2 carbon) (substrate near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:27
29	4	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) ((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate))) with ((metal metallic al aluminum) near (layer coating film))) and ((substrate with carbon) ((magnetic magneto-optical mo!) near2 (disk recording)) ((substrate near2 carbon) (substrate near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:29
30	518	((metal metallic al aluminum) near (layer coating film)) near4 (etch-stop (etch near2 stop))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:30
31	0	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate)) same ((metal metallic al aluminum) near (layer coating film)) near4 (etch-stop (etch near2 stop)))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:30
32	18	((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate)) and ((metal metallic al aluminum) near (layer coating film)) near4 (etch-stop (etch near2 stop)))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:31

33	5519	430/311,313,317,329,256.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:35
34	270	430/311,313,317,329,256.ccls. and (((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) near2 (carbon-contain\$3 c-contain\$3 ((c carbon) adj contain\$3))) ((resist photoresist photo-resist photosensitive photo-sensitive (sensitive near (photo light energy radiation))) with (pmma! polymethylmethacrylate polymethyl-methacrylate polymethyl adj methacrylate)))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:35
35	587583	(magnetic magneto-optical mo! recording optical) near2 (disc disk medium)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:39
36	233	430/311,313,317,329,256.ccls. and ((magnetic magneto-optical mo! recording optical) near2 (disc disk medium))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/18 19:39